PROCEEDINGS OF SPIE

Modeling Aspects in Optical Metrology V

Bernd Bodermann
Karsten Frenner
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Editors

23–25 June 2015
Munich, Germany

Sponsored by
SPIE

Cooperating Organisations
European Optical Society
German Scientific Laser Society (Wissenschaftliche Gesellschaft Lasertechnik e.V.)

Published by
SPIE

Volume 9526

Proceedings of SPIE 0277-786X, V. 9526

Modeling Aspects in Optical Metrology V, edited by Bernd Bodermann, Karsten Frenner, Richard M. Silver,
Proc. of SPIE Vol. 9526, 952601 · © 2015 SPIE · CCC code: 0277-786X/15/$18 · doi: 10.1117/12.2197968

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Author(s), "Title of Paper," in *Modeling Aspects in Optical Metrology V*, edited by Bernd Bodermann, Karsten Frenner, Richard M. Silver, Proceedings of SPIE Vol. 9526 (SPIE, Bellingham, WA, 2015) Article CID Number.

ISSN: 0277-786X
ISBN: 9781628416862

Published by
SPIE
P.O. Box 10, Bellingham, Washington 98227-0010 USA
Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445
SPIE.org

Printed in the United States of America.

Publication of record for individual papers is online in the SPIE Digital Library.

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